November 2013

EV-1000 Supervision

Endpoint Control on Cluster Tools: Dry Etch, Cleaning, PECVD

- Engineering Toolbox for Plasma analysis
  - Process understanding
  - Process development
- Production Endpoint Monitoring software
  - 24/24 Run to run Product monitoring
  - Flexible & confidential recipes
  - Fab's Automation
- Quality Plug-in, R2R control
  - Database
  - Statistics
  - Multi-Runs Viewer
- Maintenance
  - Stability Health Chamber Monitoring
  - Fault Detection

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